



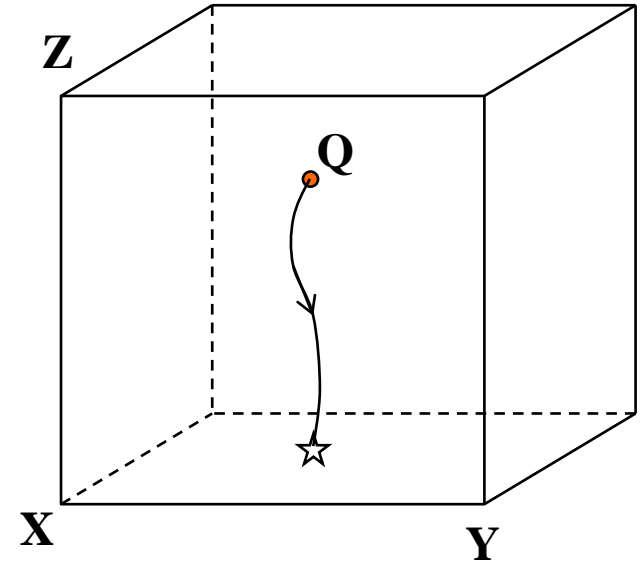
Laser measurements on single chip module

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Nikhef/Bonn LepCol meeting
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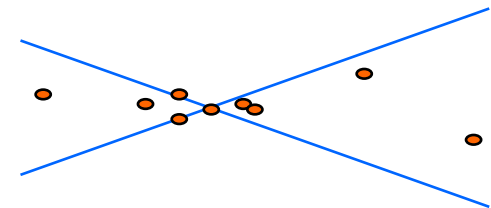
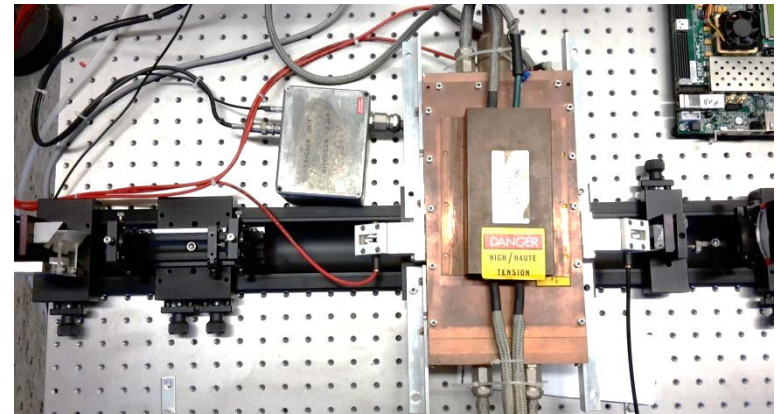
Why laser measurements?

- Fundamental method to measure drift paths and drift velocities in a drift volume in 3D
- Classical electrostatic problem
 - Create a point charge Q in a parallel E-field at a given position in space and at a given time
 - Measure the travel time and hit position at an XY plane
- By doing an XYZ scan across the whole drift volume, we get a direct measurement of the drift trajectories and local drift velocities



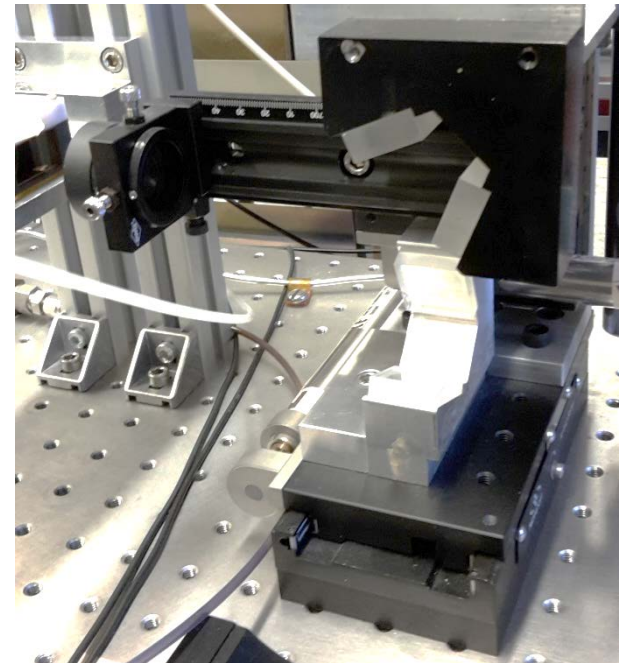
Making laser ionization

- Using focused beam pulsed UV nitrogen laser (Nikhef type IA)
 - Near UV: 337 nm (3.7 eV)
 - < 1 ns duration
- Pulse frequency ~ 3 Hz
 - MOPA setup => near diffraction limit
 - Beam diameter ~10 mm, focused at 60 mm focal length
 - Achromatic composite lens to avoid spherical aberration
- Ionization in chamber gas by **double photon** process
 - Proportional to square of light intensity
 - $2 * 3.7 = 7.4$ eV
 - Tetra-Methyl-Phenylene-Diamine (TMPD) as ionizing compound
 - Concentration $\ll 1$ ppM
- => highest ionization density (e⁻/cm) in focal area



Beam management

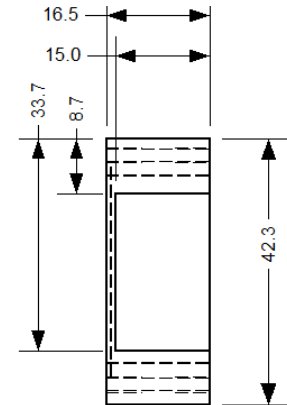
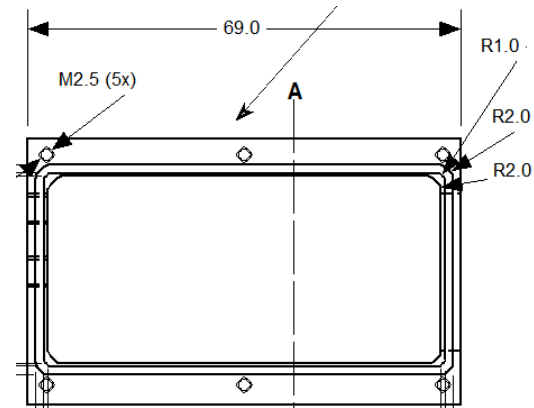
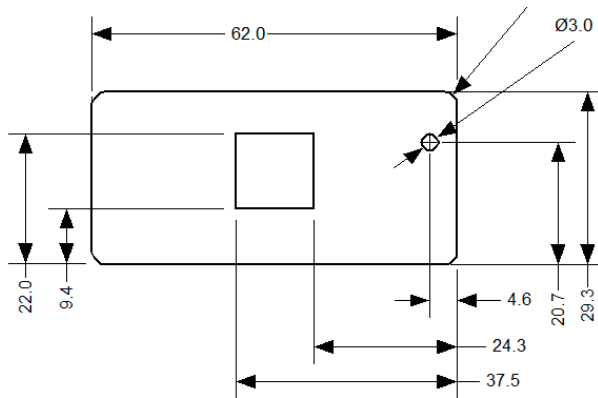
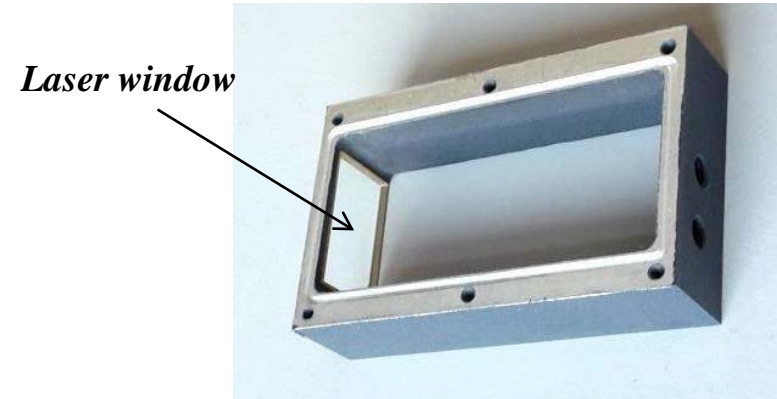
- Detector kept on fixed position, scanning with focal point
- Position of focal point exclusively determined by two parameters
 - Position of focussing lens
 - Direction of incoming beam
- Lens mounted on remotely controlled XYZ stage system
 - Allowing precise positioning with sub μm resolution
- Beam direction stabilized by two pentamirror systems
- Ionization tuned by neutral density wedge filter



Stages with two pentamirror sets + focussing lens

- Using TPX3 with InGrid from Yevgen
- Field cage from conductive plastic
 - Semitron ESD 490 HD
 - Top and bottom edge made conductive by silver paint
- Drift length ~15.5 mm
- Guard aperture 13.2 * 12.6 mm
 - Cutting part of active pixels
 - 12.6 of 14.1 mm

Single module setup

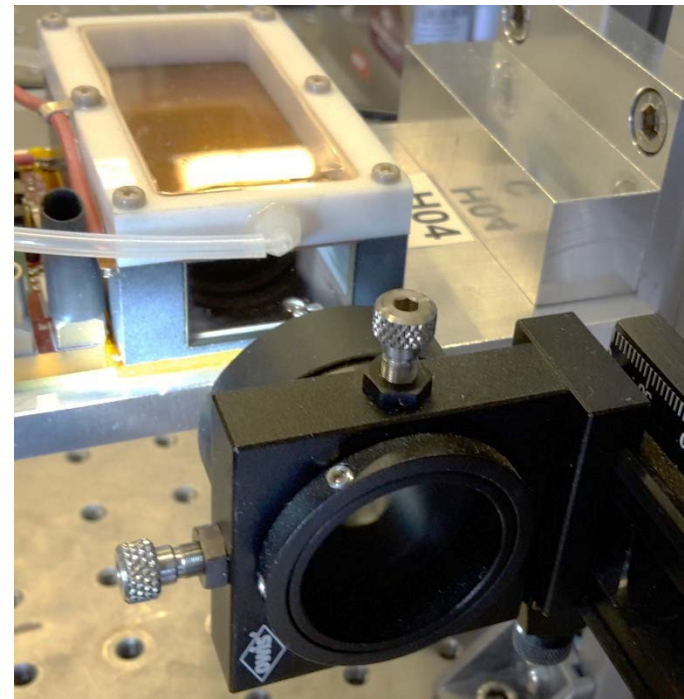
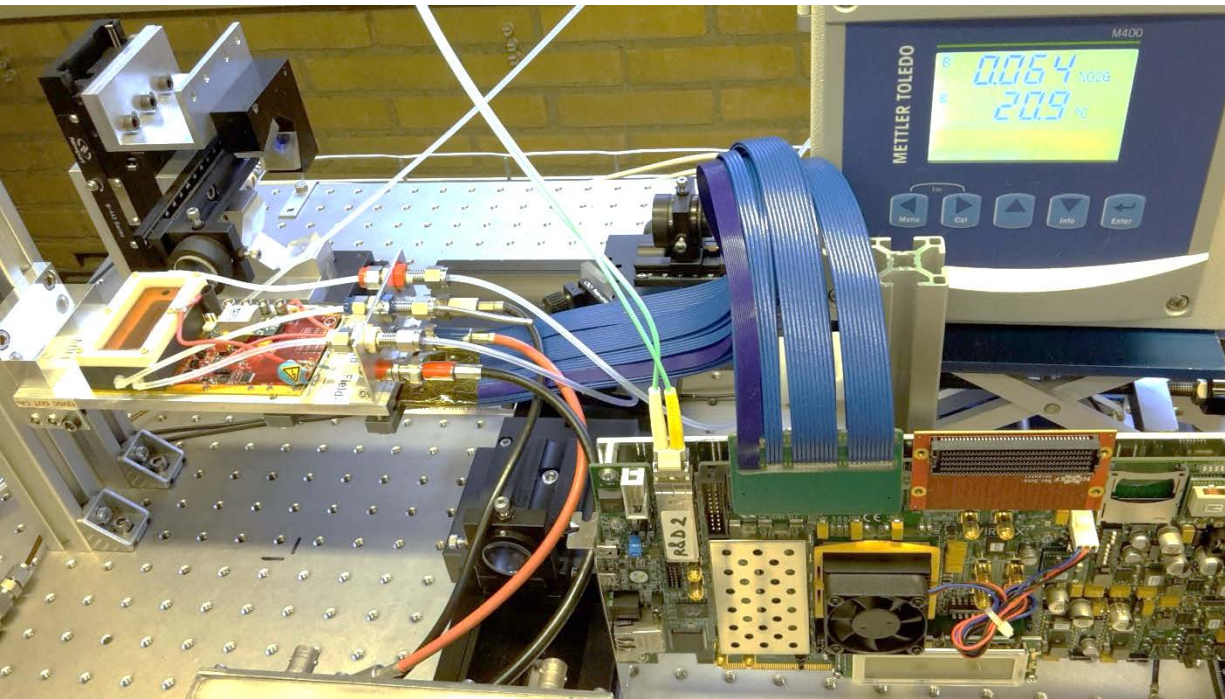


Coppered kapton 50 um



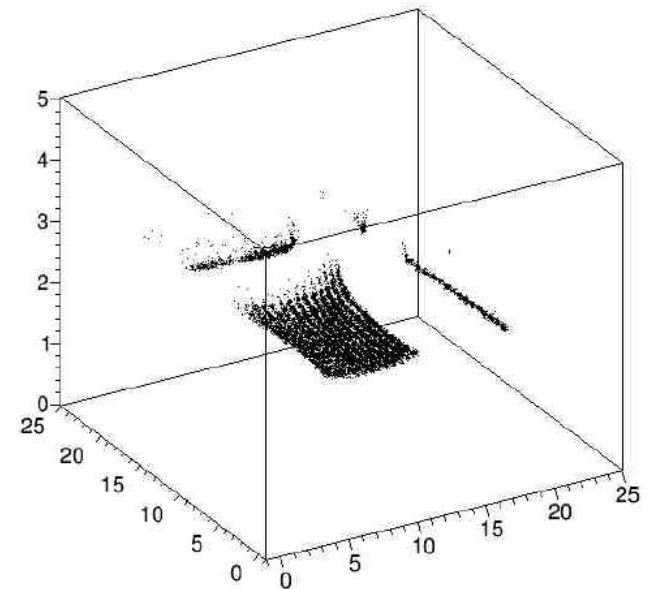
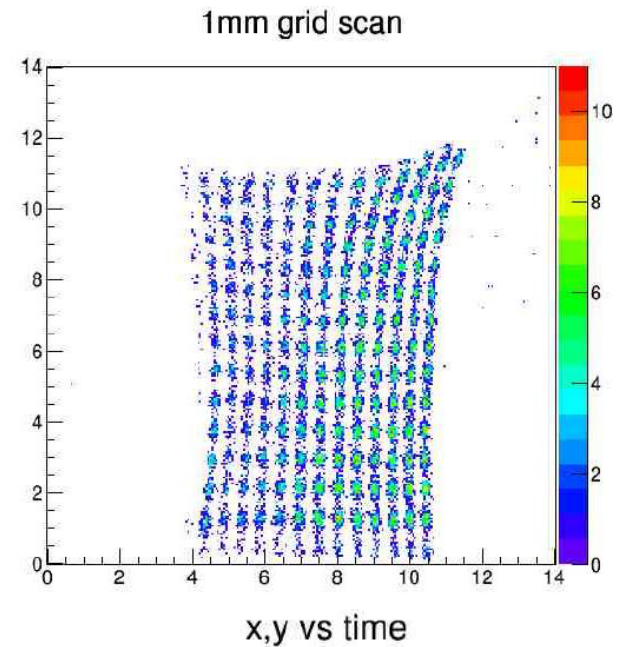
Status

- Detector assembled and installed
 - Chip H4 (class C)
- Services connected
 - Gas, HV, SPIDR board, stages
- Commissioning in progress
 - Remote control XYZ stages
 - Optical measurement of height of grid, guard electrode, cathode foil
 - Verifying voltage distribution along field cage
 - Entering the trigger time (fast photodiode) in SPIDR



Running conditions

- Tune gas gain to SE hit efficiency > 80%
- Tune laser intensity such that hit efficiency per pixel per laser shot < 10%
 - => double electron hits < 5% of total hits on that pixel (Poisson statistics)
- Collect 50 laser shots on same position
 - Use the hits to calculate a master point (centre of gravity)
- Move one stage to next position (over 1 mm or so) and take another 50 shots
- Example of 3D run
 - Collecting data from XYZ matrix of 1 * 1 * 1 mm step across 15 * 15 * 15 mm
 - => 3375 master points
 - => 168750 laser shots
 - => 15.6 hour running



*Earlier measurements of Harry's
QUAD focus chamber by Wouter Bos*

SPARE

- In progress/ under discussion
- Going from one chip to another on same carrier
 - 3 pixels sacrificed
- Going from one chip to another on neighbouring carrier
 - 4 pixels sacrificed
 - 28.6 => 28.435

List of parameters

**First approach, to be updated
Put this on a Nikhef server with
read access to everybody (incl Bonn)**

Mechanical									
Item	Values (um)			Angle (mrad)		Reference			remarks
	X	Y	Z	hor. Plane	vert. plane	X	Y	Z	
position InGrid of chips	± 20	± 20	± 20	1	1	PCB ref marks	PCB ref marks	foot T	
chip to chip distance		60							
last pixel Ch1 1st pixel CH2		165							
chip to chip distance mod 1 to mod 2		115							
last pixel mod1 to 1st pixel mod 2		220							
module to module pitch		28435							
position PCB ref marks	± 20	± 20	± 100	1	1	carrier edge	carrier edge	carrier foot	
Top guard electrode	± 50	± 50	500± 20	10	1	carrier edge	carrier edge	chip dyke	
chip edge to PBC			100						
chip dimension edge to edge			14130						
Electrical									
	Value								
Grid potential Vgrid (V)	~-400± 4								
Grid supply resistor (Ω)	100M								each chip
drift field E (V/cm)	-100								
Guard potential (V)	Vgrid + E*Zguard								
Guard supply resistor (Ω)	100M								

Assembly / alignment method

- Mount PCB on carrier
 - Refer to two carrier edges using jig with reference marks
 - AND refer to reference marks on PCB
- Mount chips on carrier
 - 2 chips on one side simultaneously
 - XY: refer to grid hole pattern
 - rough alignment using bonding pads ($N \times 55 \mu\text{m}$)
 - AND refer to reference marks on PCB
 - Z: refer to grid (fixed height of alignment jig)
- Mount guard electrode
 - XY: refer edges to reference marks on PCB (tolerance $100 \mu\text{m}$)
 - Provide a 1 mm hole at the PCB reference marks
 - Z: let sides of the guard rest on dykes
 - Guard should fabricated bit hollow
- Module to module
 - XY: refer to PCB reference marks

- Sides
 - 2 x 3 pixels lost
- Top
 - No pixels lost
- Bottom
 - No pixels lost

dykes

